

### IN THE CLAIMS

Please amend claims 1-5, and add new claims 21-22 as follows:

1. (Currently Amended) A semiconductor integrated circuit device, comprising:
  - a plurality of bonding pads arranged along ~~at least one~~ of four sides of ~~[[a]]~~ at least one semiconductor chip embedded in the semiconductor integrated circuit device;
  - at least one inspection pad on another one of the four sides of the semiconductor chip; and
  - a corresponding connection wire, which is laid outside an input/output buffer area of the chip for each of said bonding pads, for connecting said each bonding pad with the inspection pad.
2. (Original) The semiconductor integrated circuit device as claimed in claim 1, wherein each of a plurality of semiconductor chips of said semiconductor integrated circuit device being arranged on a wafer so as to arrange the sides with the inspection pads of said chips in parallel.
3. (Original) The semiconductor integrated circuit device as claimed in claim 1, wherein at least one connection wire is laid inside the input/output buffer area.
4. (Original) The semiconductor integrated circuit device as claimed in claim 1, wherein each said connection wire has the same length.
5. (Currently Amended) The semiconductor integrated circuit device as claimed in claim 1, wherein~~[[:]]~~
  - the inspection pads and the connection wires are laid in a scribing area; and
  - the inspection pads and the bonding pads are arranged in a row or zigzag such that the inspection pads and the connection wires are to be removed from the semiconductor integrated circuit device when the semiconductor integrated circuit device is cut off from a wafer at the scribing area after the semiconductor integrated circuit device is inspected with probe needles.

6. (Withdrawn) The semiconductor integrated circuit device as claimed in claim 1, wherein:
  - the connection wires are laid in at least one wiring layer; and
  - GND lines are laid between the connection wires or at least one GND layer is formed between the wiring layers.
7. (Withdrawn) The semiconductor integrated circuit device as claimed in claim 1, wherein an electrostatic discharge protection element is disposed in the vicinity of each said inspection pad.
8. (Withdrawn) A semiconductor integrated circuit package having leads on four sides, comprising:
  - a semiconductor integrated circuit device with bonding pads laid along one pair of opposite sides of the four sides; and
  - a table for supporting the semiconductor integrated circuit device,wherein the bonding pads along the pair of opposite sides of the semiconductor integrated circuit device are connected with leads along the four sides of the package.
9. (Withdrawn) The package as claimed in claim 8, wherein the leads comprises:
  - first outer leads arranged along a first side of the package;
  - second outer leads arranged along a second side, perpendicular to the first side, of the package;
  - first inner leads corresponding to the first outer leads but being bent toward the second side; and
  - second inner leads corresponding to the second outer leads.
10. (Withdrawn) The package as claimed in claim 9, wherein the pads of the semiconductor integrated circuit device are arranged zigzag, and
  - bonding wires for connecting the pads of the semiconductor integrated circuit device to the tips of the inner leads have significantly the same length.

11. (Withdrawn) The package as claimed in claim 8, wherein an extension line of one side of the semiconductor integrated circuit device and an extension line of the closest side of the package are not parallel but intersect at a fixed angle.
12. (Withdrawn) The package as claimed in claim 11 wherein the fixed angle is 45°.
13. (Withdrawn) The semiconductor integrated circuit device as claimed in claim 1, wherein at least one electrostatic discharge protection element is provided for at least one of the inspection pads and the input/output buffer area.
14. (Withdrawn) The semiconductor integrated circuit device as claimed in claim 3, wherein said at least one connection wire laid inside the input/output buffer area circumvents or crosses over a package of the chip to extend from the bonding pad to the inspection pad.
15. (Withdrawn) The package as claimed in claim 8, where the leads constitute the table for supporting.
16. (Withdrawn) The package as claimed in claim 8, wherein at least one electrostatic discharge protection element is provided for at least one of the pads.
17. (Withdrawn) The package as claimed in claim 9, wherein at least one of the second inner leads have tips arranged zigzag with respect to tips of the first inner leads.
18. (Withdrawn) The package as claimed in claim 9, wherein the second inner leads are connected to the second outer leads via wires outside of the semiconductor integrated circuit device and inside the package.
19. (Withdrawn) The package as claimed in claim 9, wherein each of the bonding pads is either connected to the inner leads with bonding wires, and the bonding wires are laid outside an input/output buffer area of the chip.
20. (Withdrawn) A semiconductor integrated circuit device, comprising:

a plurality bonding pads arranged along at least one side of a least one semiconductor chip embedded in the semiconductor integrated circuit device;

at least one inspection pad on another side of the semiconductor chip; and

a corresponding connection wire for each of said bonding pads for connecting said each bonding pad with the inspection pad,

wherein at least one of the bonding pads, the inspection pads and the connection wire is to be removed from the device when the device is cut off from a wafer.

21. (New) The semiconductor integrated circuit device as claimed in claim 1, wherein the connection wire is laid inside an area where the semiconductor chip is formed.
22. (New) The semiconductor integrated circuit device as claimed in claim 1, further comprising an electrostatic discharge protection element coupled to the inspection pad.